Received: 4-2-04

FORM PTO-1449 INFORMATION DISCLOSURE STATEMENT			ATTY DOCKET NO. 51898	SERIAL NO. 10/816,356 Not Yet Assigned					
				APPLICANT(S): Woelk et al.					
				FILING DATE: ART UNIT: 28 13 Herewith 04/02/2004 Not Yet Assigned					
		UNITED ST	TATES PATENT	DOCUMENTS					
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S.W.S.	AB	3,446,824	05/27/1969	K. Moedritzer					
S.W.X.	AC	4,506,815	03/26/1985	Melas et al.		_			
J.W.S.	AD	3,470,220	09/30/1969	Moedritzer et al.					
2WQ.	AE	5,120,394	06/09/1992	Mukai					
Soll, S.	AF	5,502,227	03/26/1996	Kanjolia et al.		-			
2112	AG	5,755,885	05/26/1998	Mikoshiba et al.					
SWL	AH	6,099,903	08/08/2000	Kaloyeros et al.		_			
INIX.	ΑI	6,214,729	04/10/2001	Uhlenbrock et al.			,		
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J.W.L.	AK	6,306,217	10/23/2001	Uhlenbrock et al.					
IND.	AL	6,391,803	05/21/2002	Kim et al.					
I.W.S.	AM	6,444,038	09/03/2002	Rangarajan et al.		_			
I.D.L.	AN	6,444,041	09/03/2002	Vaartstra		(
Q.W.Z.	AO	6,444,818	09/03/2002	Uhlenbrock et al.					
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Examiner:	tethen	W. Smoo	t	Date: February	20,	200	6		

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					NG DATE: with 04/02/2001	ART UI	T: 2	813 I		
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LN.S.	CC	Hoffman et al., "Plasma-enhanced chemical vapor deposition of silicon, germanium, and tin nitride thin films from metalorganic precursors", J. Vac. Sci. Technol. A 13(3), May/Jun 1995, pp. 820-825.								
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